

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



In re the Application of

Makoto KOBAYASHI et al.

Application No.: 09/830,434

Filed: April 26, 2001

For: POLISHING PAD AND POLISHING METHOD
FOR SEMI-CONDUCTOR WAFER

Group Art Unit: 3723

Examiner: H. Shakeri

Docket No.: 109352

MAIL STOP RCE

#9/RCE

**LARGE ENTITY REQUEST FOR
CONTINUED EXAMINATION UNDER 37 C.F.R. §1.114**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

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OCT 22 2003

TECHNOLOGY CENTER R3700

Sir:

In accordance with the provisions of 37 C.F.R. §1.114, Applicants hereby request continued examination. Applicants further request entry and consideration of the:

- ☒ submission filed September 17, 2003.
- ☐ attached submission.
- ☐ The submission filed [Date] is not to be entered.

The above-identified application was filed on or after June 8, 1995. Thus, entry is proper under 37 C.F.R. §1.114(d).

Attached hereto is our check no. 147450 in the amount of ☒ \$770.00 as payment of the fees set forth in 37 C.F.R. §1.17(e). The Commissioner is hereby authorized to charge any additional fees or credit any overpayment associated with this communication to Deposit Account No. 15-0461. Two duplicate copies of this page are enclosed.

Respectfully submitted,

William P. Berridge
Registration No. 30,024

Joel S. Armstrong
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WPB:JSA:CWB/rav

Date: October 17, 2003

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**DEPOSIT ACCOUNT USE
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